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Plurals

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"3532429"	"3880524"	"3985447"	"4320971"	"4494872"	"4555767"	"4948259"
"4983039"	"4984894"	"5166755"	"5227861"	"5337150"	"5416594"	"5450205"
"5587792"	"5642196"	"5643044"	"5646734"	"5658183"	"5663797"	"5667424"
"5685766"	PN.					

	U	+	Document ID	Issue Date	Pages	Title	Current OR	Current XR	Retrieval C	Inventor	S	C	P	3	
1	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 3532429 A	19701006	3	MULTICHANNEL ATOMIC ABSORPTION SPECTROMETER	356/320	356/323; 356/329			<input checked="" type="checkbox"/>	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
2	<input type="checkbox"/>	<input type="checkbox"/>	US 5685766 A	19971111	10	Polishing control method	451/36	451/41; 451/5		Mattingly, Wayne et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
3	<input type="checkbox"/>	<input type="checkbox"/>	US 5667424 A	19970916	9	New chemical mechanical planarization (CMP) and point	451/6	451/285; 451/286		Pan, Yang	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
4	<input type="checkbox"/>	<input type="checkbox"/>	US 5663797 A	19970902	11	Method and apparatus for detecting the endpoint in the	438/16	438/693; 451/6		Sandhu, Gurtej Singh	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
5	<input type="checkbox"/>	<input type="checkbox"/>	US 5658183 A	19970819	28	System for real-time control of semiconductor wafer polishing	451/5	250/559.27; 356/150.29		Sandhu, Gurtej S. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
6	<input type="checkbox"/>	<input type="checkbox"/>	US 5646734 A	19970708	10	Method and apparatus for independently measuring the	356/632	356/479; 356/107		Venkatesh, Shalini et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
7	<input type="checkbox"/>	<input type="checkbox"/>	US 5643044 A	19970701	19	Automatic chemical and mechanical polishing system	451/5	451/168; 451/286		Lund, Douglas E.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
8	<input type="checkbox"/>	<input type="checkbox"/>	US 5642196 A	19970624	12	Method and apparatus for measuring the thickness of a	356/632	356/479; 356/107		Alves, Ronald V. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
9	<input type="checkbox"/>	<input type="checkbox"/>	US 5587792 A	19961224	29	Apparatus and method for measuring thickness of thin	356/497	250/559.27; 356/104		Nishizawa, Seiji et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
10	<input type="checkbox"/>	<input type="checkbox"/>	US 5450205 A	19950912	29	Apparatus and method for real time measurement of thin	356/632	216/60; 356/104		Sawin, Herbert H. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
11	<input type="checkbox"/>	<input type="checkbox"/>	US 5416594 A	19950516	10	Surface scanner with thin film	356/237.5	356/632		Gross, Kenneth P. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>